

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	40289	(substrate or semi\$1conductor or semiconductor or substrate or wafer) same (piezoelectric)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:17
L2	40289	(substrate or semi\$1conductor or semiconductor or wafer) same (piezoelectric)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:17
L3	18525	(substrate or semi\$1conductor or semiconductor or wafer) same (piezoelectric and element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:17
L4	2327	(substrate or semi\$1conductor or semiconductor or wafer) same (piezoelectric and element) same (drive or driving)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:18
L5	533	4 and (clean\$3 or wash\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:52
L7	2	"6259960".pn.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:27
L9	1	(koji adj Ikeda).in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:28
L10	8	09/878773	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:28
L11	662	134/61	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:52

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L15	262	134/62	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L16	186	134/63	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L17	346	134/66	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L18	60	134/69	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L19	127	134/78	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L20	158	134/80	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L21	214	134/84	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L22	142	134/85	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L23	104	134/86	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56
L24	90	134/89	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:56

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S1	9	"134".clas. and (substrate or semi\$1conductor or semiconductor or substrate or wafer) and (holder or holding) and ((laser near gauge) or (image near processing))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:18
S2	1	"68".clas. and (substrate or semi\$1conductor or semiconductor or substrate or wafer) and (holder or holding) and ((laser near gauge) or (image near processing))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:18
S3	10972	(substrate or semi\$1conductor or semiconductor or substrate or wafer) and (holder or holding) and ((laser near gauge) or (image near processing))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:24
S4	8040	S3 and transfer\$4	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:22
S5	8040	S4 and (clean\$3 or wash\$3 or process\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:22
S6	1962	S5 and (tank or container)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:22
S7	1653	S6 and detect\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/23 23:23
S8	810	(substrate or semi\$1conductor or semiconductor or substrate or wafer) and (holder or holding) and ((laser near gauge) or (detect\$3 same (image near processing))) and (clean\$3 or wash\$3 or process\$3) and (tank or container)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2006/07/24 10:16